What is claim d is:

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An electron source comprising:

an anode;

a cathode comprising an electron emitting portion and having a

cathode axis;

an electromagnetic radiation source adapted to generate an electromagnetic radiation beam to heat the cathode; and

a lens adapted to direct the electromagnetic radiation beam onto the cathode, the lens having a lens axis that forms an acute angle with, or is substantially parallel to, the cathode axis.

- 2. An electron source according to claim 1 wherein the cathode comprises a beam-receiving portion and the lens is adapted to direct the electromagnetic radiation beam onto the beam-receiving portion.
- 3. An electron source according to claim 2 wherein the beamreceiving portion is a different portion of the cathode than the electron emitting portion.
- 4. An electron source according to claim 2 wherein the beam-receiving portion comprises a substantially concave surface.
- 5. An electron source according to claim 1 wherein the electron emitting portion comprises tungsten.
- 6. An electron source according to claim 1 wherein the cathode comprises a rod that terminates in the electron emitting portion, and wherein the lens is attached to the rod.
- 7. An electron source according to claim 1 wherein the electromagnetic radiation source is adapted to heat the cathode to at least about 1800 Kelvin.

An electron source according to claim 1 wherein the lens comprises aluminum oxide.

- 9. An electron source according to claim 1 comprising an electromagnetic radiation detector to detect radiation reflected from the cathode to determine a property of the cathode.
- 10. An electron beam apparatus to register an electron beam pattern on a substrate, the apparatus comprising:

a vacuum òhamber;

a substrate support to support a substrate;

an electron source to provide an electron beam in the vacuum chamber, the electron source comprising (a) an anode, (b) a cathode comprising an electron emitting portion and having a cathode axis, (c) an electromagnetic radiation source adapted to generate an electromagnetic radiation beam to heat the cathode, and (d) a lens adapted to direct the electromagnetic radiation beam onto the cathode, the lens having a lens axis that forms an acute angle with, or is substantially parallel to, the cathode axis; and

an electron beam modulator and scanner to modulate and scan the electron beam across the substrate to register an electron beam pattern on the substrate.

- 11. An apparatus according to claim 10 wherein the cathode comprises a beam-receiving portion and the lens is adapted to direct the electromagnetic radiation beam onto the beam-receiving portion.
- 12. An apparatus according to claim 11 wherein the beam-receiving portion is a different portion than the electron emitting portion.
- 13. An apparatus according to claim 11 wherein the beam-receiving portion comprises a substantially concave surface.
- 14. An apparatus according to claim 10 wherein the electron emitting portion comprises tungsten.

15. An apparatus according to claim 11 comprising a rod that connects the lens and the beam-receiving portion of the cathode.

- 16. An apparatus according to claim 10 wherein the electromagnetic radiation source is adapted to heat the cathode to at least about 1800 Kelvin.
- 17. An apparatus according to claim 10 wherein the lens comprises aluminum oxide.
- 18. An apparatus according to claim 10 wherein the electron source comprises an electromagnetic radiation detector to detect radiation reflected from the cathode to determine a property of the cathode.
- 19. A method of generating electrons from an electron source comprising an anode, and a cathode having an electron emitting portion and a cathode axis, the method comprising:
 - (a) negatively biasing the cathode relative to the anode; and
- (b) directing an electromagnetic radiation beam onto the cathode at an acute angle with, or substantially parallel to, the cathode axis.
- 20. A method according to claim 19 comprising directing the electromagnetic radiation beam onto a beam-receiving portion of the cathode.
- 21. An method according to claim 19 comprising heating the cathode to at least about 1800 Kelvin.
- 22. An method according to claim 19 comprising detecting a radiation reflected from the cathode and determining a property of the cathode.



β. An electron source comprising:

an anode;

a cathode comprising an electron emitting portion having a tip, a beam-receiving portion, and a cathode axis;

a laser beam source adapted to generate a laser beam to heat the cathode; and

a lens adapted to focus the laser beam onto the cathode, the lens being supported by a rod that is substantially parallel to the cathode axis and terminates in the electron emitting portion of the cathode.

- 24. An electron source according to claim 23 wherein the lens comprises a lens axis that forms an acute angle with or is substantially parallel to, the cathode axis.
- 25. An electron source according to claim 23 wherein the beam-receiving portion is a different portion of the cathode than the electron emitting portion.
- 26. An electron source according to claim 23 wherein the beam-receiving portion comprises a substantially concave surface.
- 27. An electron source according to claim 23 wherein the electron emitting portion comprises tungsten.
- An electron source according to claim 23 wherein the electromagnetic radiation source is adapted to heat the cathode to at least about 1800 Kelvin.
- 29. An electron source according to claim 23 wherein the lens comprises aluminum oxide.
- 30. An electron source according to claim 23 comprising an electromagnetic radiation detector to detect radiation reflected from the cathode to determine a property of the cathode.

A method of registering an electron beam pattern on a substrate, the method comprising:

- (a) \placing a substrate on a substrate support;
- (b) generating an electron beam by (i) biasing a cathode relative to an anode, and (ii) generating an electromagnetic radiation beam and directing the electromagnetic radiation beam onto the cathode to heat the cathode; and
- (c) modulating and scanning the electron beam across the substrate to register an electron beam pattern on the substrate.
- 32. A method according to claim 31 comprising directing the electromagnetic radiation beam on a beam-receiving portion of the cathode.
- 33. An method according to claim 31 wherein the electromagnetic radiation beam is capable of heating the cathode to at least about 1800 Kelvin.

